

Supporting information

Stretchable and stable neuromorphic tactile system

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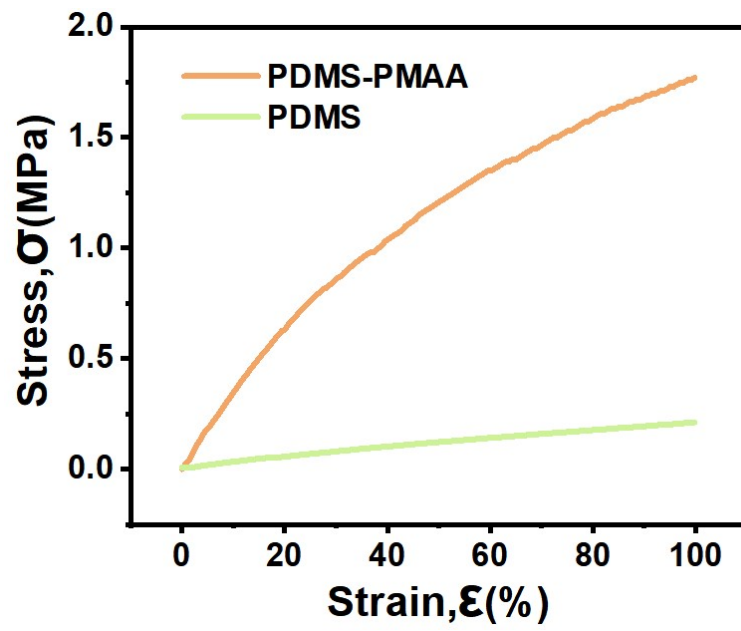


Figure S1. Comparison of stress-strain curves of PDMS-PMAA and PDMS.

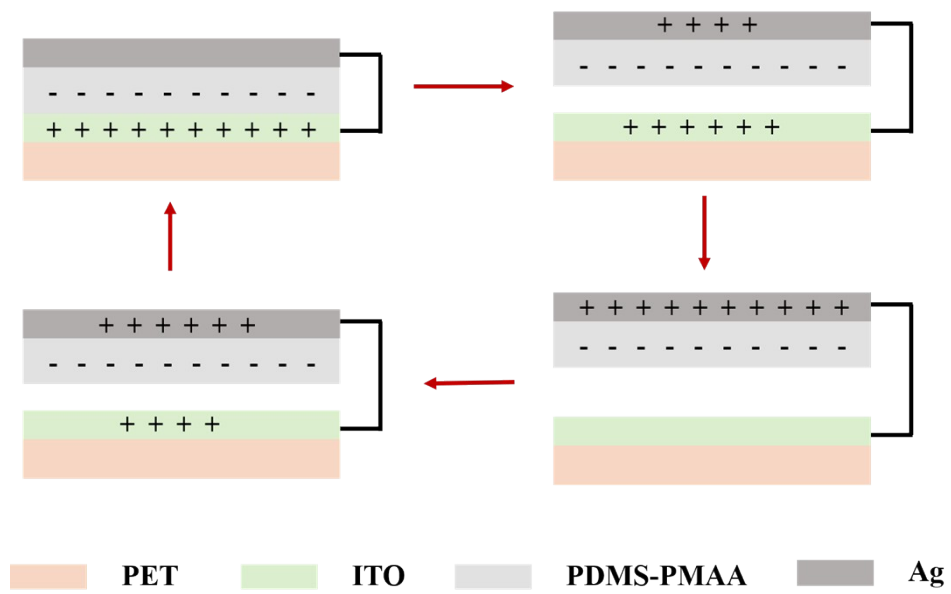


Figure S2. Working mechanism of TENG.

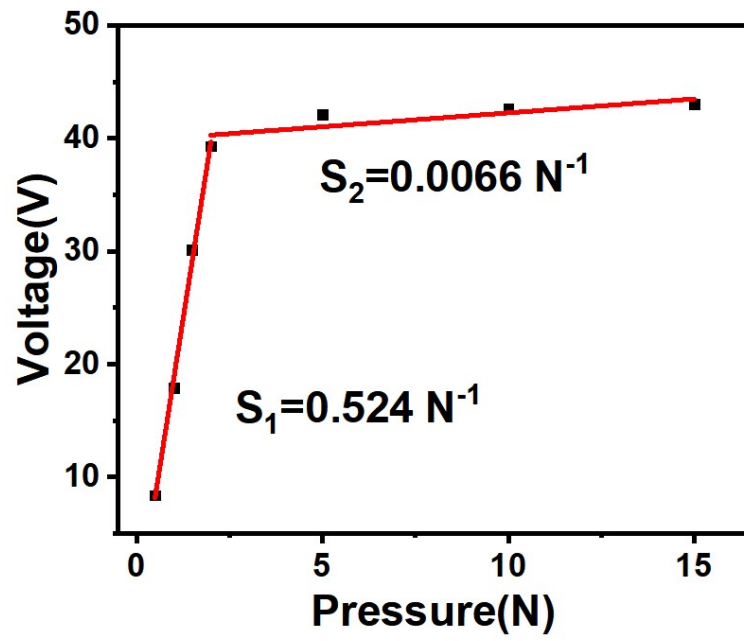


Figure S3. The pressure sensitivity of TENG.

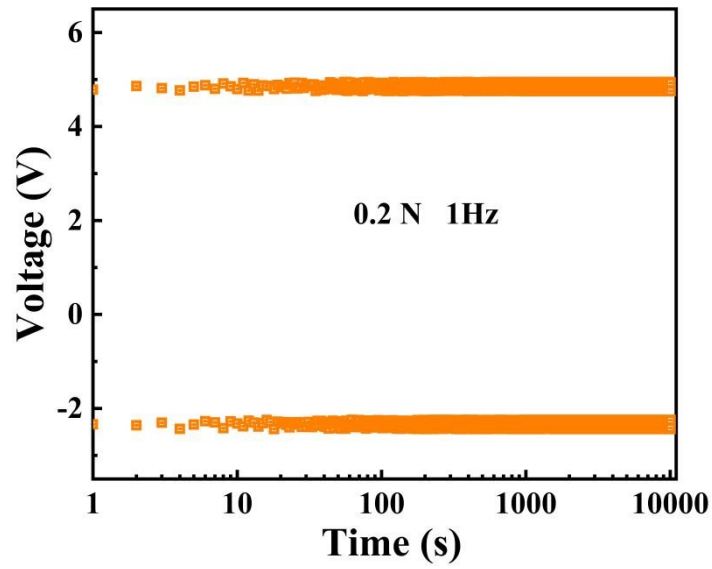


Figure S4. The stability of TENG.

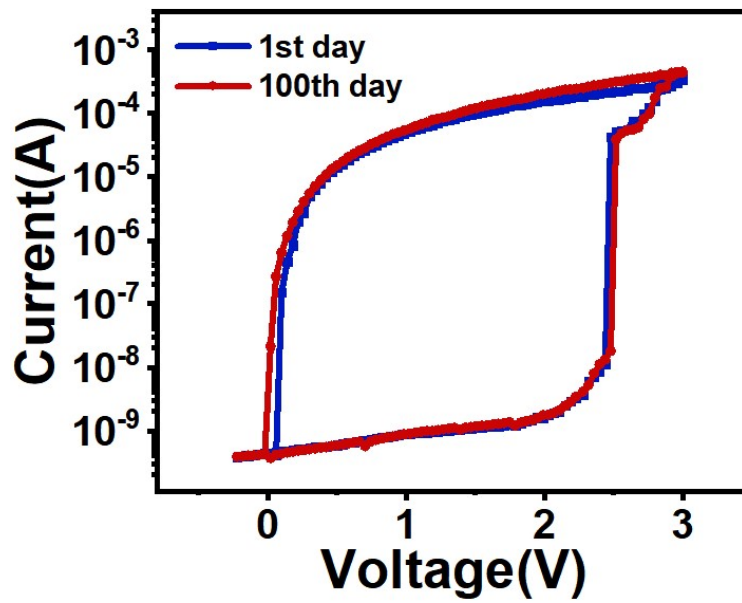


Figure S5. Threshold switching characteristics stability of the artificial neuron.

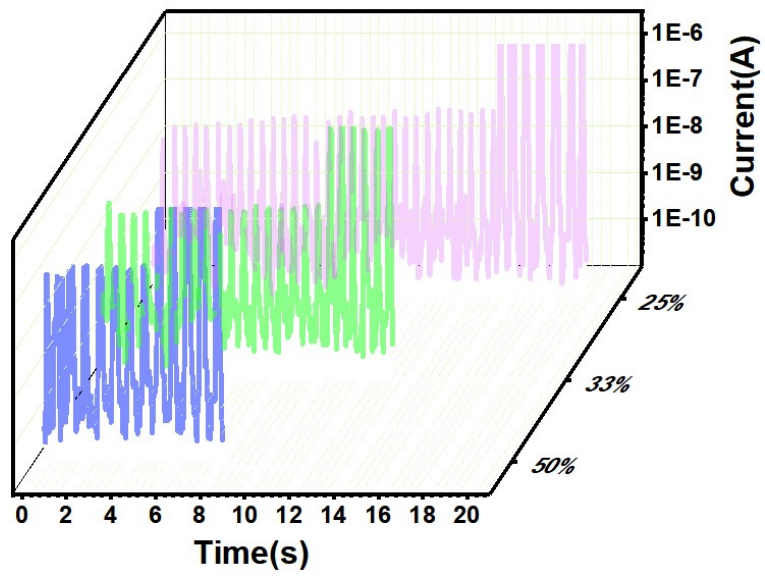


Figure S6. The firing time is affected by the duty ratio of stimulation pulse (50%, 33%, 25%).

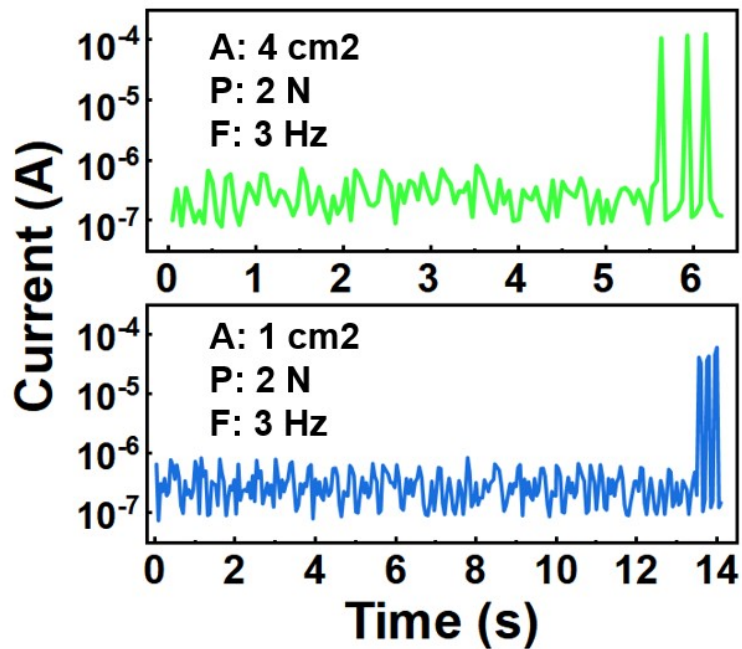


Figure S7. The firing time is affected by the pressure area on TENG.

Table S1 The comparison between other strain-isolated stretchable substrates research and this work.

Materials	Methods	Self-powered	Strain intensity	Ref.
Ecoflex/Liquid	Microfluidic space	No	50%	1
Acetate	Rigid-soft combination	No	50%	2
PI	Cut-transfer-release	No	200%	3
PDMS	Microislands	No	45%	4
PDMS	3D buckling assembling	No	100%	5
Cu	wrinkled	No	40%	6
PDMS-PMAA	Double-network	Yes	60%	This work

References

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